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(54) Title: AUTOMATED SEMICONDUCTOR PROCESSING SYSTEM

(57) Abstract

An automated semiconductor processing system has an indexer bay (75) perpendicularly aligned with a process bay (94) within a clean air enclosure (54). An indexer (72) in the indexer bay provides stocking or storage for work in progress semiconductor wafers. Process chambers (68, 70) are located in the process bay. A process robot (66) moves between the indexer bay and process bay to carry semiconductor wafers to and from the process chambers. The process robot has a robot arm (255) vertically moveable along a lift rail (254). Semiconductor wafers are carried offset from the robot arm, to better avoid contamination. The automated system is compact and requires less clean room floor space.

